

Notice of References Cited	Application/Control No. 10/683,904	Applicant(s)/Patent Under Reexamination SPIEGELMAN ET AL.	
	Examiner Sharidan Carrillo	Art Unit 1746	Page 1 of 1

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	C	US-5,846,338	12-1998	Bonora et al.	134/11
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NON-PATENT DOCUMENTS

*		Include as applicable: Author, Title Date, Publisher, Edition or Volume, Pertinent Pages)
	U	Kern, Werner; "Handbook of Semiconductor Wafer Cleaning Technology", 1993, pages 88-89
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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
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